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PATENT

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 09/881,641

Attorney Docket: DP-302459

Filing Date: 06/14/2001

Group Art Unit: 1764

Applicant: Michael R. Foster et al.

Examiner: Tran, Hien Thi

Title: APPARATUS AND METHOD FOR MAT PROTECTION OF NON-THERMAL PLASMA REACTOR

Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

PROVISIONAL ELECTION

Sir:

This is in response to the Office Action mailed September 16, 2004, imposing a Restriction Requirement between:

- I. Claims 1-20, directed to a non-thermal reactor; and
- II. Claims 21-30, directed to a method for forming a non-thermal reactor.

In response to the Restriction Requirement, Applicant provisionally elects to prosecute Group I, claims 1-20. Nevertheless, Applicants respectfully traverse the requirement.

The Group I claims call for a non-thermal reactor comprising a mat retaining the plasma-generating substrate within the housing. Group II claims are drawn to the method that includes retaining the plasma-generating substrate within the housing with a mat and a retaining device. Even a causal read of these claims reveals that they are merely different aspects of but a single